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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10091983	FILING DATE 03/06/2002	CLASS 134432	SUBCLASS 591	GAU 1746	2823 NEG. REF. EXAM	EXAMINER TOLEDO
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**CONTINUING DATA VERIFIED:

** FOREIGN APPLICATIONS VERIFIED:

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO CS01-067
35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no		
Verified and Acknowledged Examiners's initials		
TITLE : Ultra-thin gate oxide through post decoupled plasma nitridation anneal		

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheets Drawn	Figs. Drawn
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner	
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